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HWA
PATENT
Customer No. 227852
Attorney Docket No. 04329-2566400
51303

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
SHINICHI ITO et al.) Group Art Unit: 2823
)
Application No.: 09/842,403) Examiner: M. Estrada
)
Filed: April 26, 2001)
)
For: FILM FORMATION METHOD,)
SEMICONDUCTOR ELEMENT)
AND METHOD THEREOF, AND)
METHOD OF MANUFACTURING)
A DISK-SHAPED STORAGE)
MEDIUM)

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Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT

In reply to the Office Action dated December 4, 2002, to which the period for reply has been extended through May 5, 2003 (May 4th being a Sunday) by a request for extension of time of two months and requisite fee payment filed concurrently herewith, please amend the application as follows:

IN THE CLAIMS:

Please amend claims 1, 2, and 4, as follows:

1. (Amended) A method of forming a solution film on an in-process substrate by using a dropping section for dropping liquid and an in-process substrate just under said dropping section, maintaining the liquid dropped from said dropping section on said

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